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Attorney Docket no: SEL 246

IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

In re Application of:

Koichiro TANAKA

Serial No.: 09/812,529

Filed: March 20, 2001

For: Method of Manufacturing A Semiconductor  
Device

Examiner: R. Booth

Art Unit: 2812

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Shannon Wallace

Name of applicant, assignee, or Registered Rep.

Shannon Wallace 2/6/04  
Signature Date

Commissioner for Patents  
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**RESPONSE F (AFTER FINAL)**

Applicant has the following response to the Final Rejection of November 6, 2003.

In the Final Rejection, Claims 1-13 continue to be allowed

Claims 14-17, 23-30 and 41

The Examiner, however, rejects Claims 14-17, 23-30 and 41 under 35 USC 103 as being unpatentable over Yamazaki et al. 5,365,080 in view of Yamazaki et al. 5,627,084. This rejection is respectfully traversed.

The rejected claims are directed to a method of manufacturing a semiconductor device and recite irradiating a crystalline semiconductor film with a second laser (having a wavelength of 532 nm or 370-570 nm) after an amorphous semiconductor film with a first laser to form the crystalline